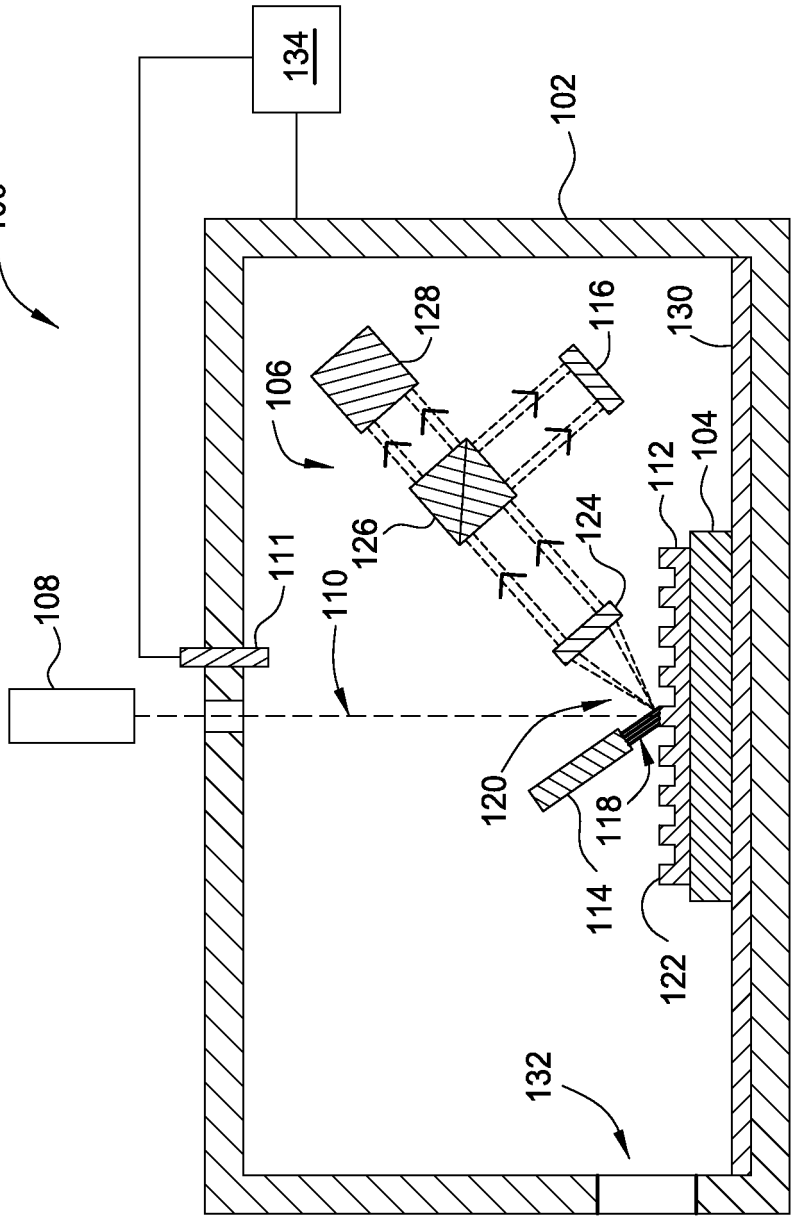

134
102
100
128
116
130
106
104
112
126
124
111
110
108
120
118
114
122
132

FIG. 1

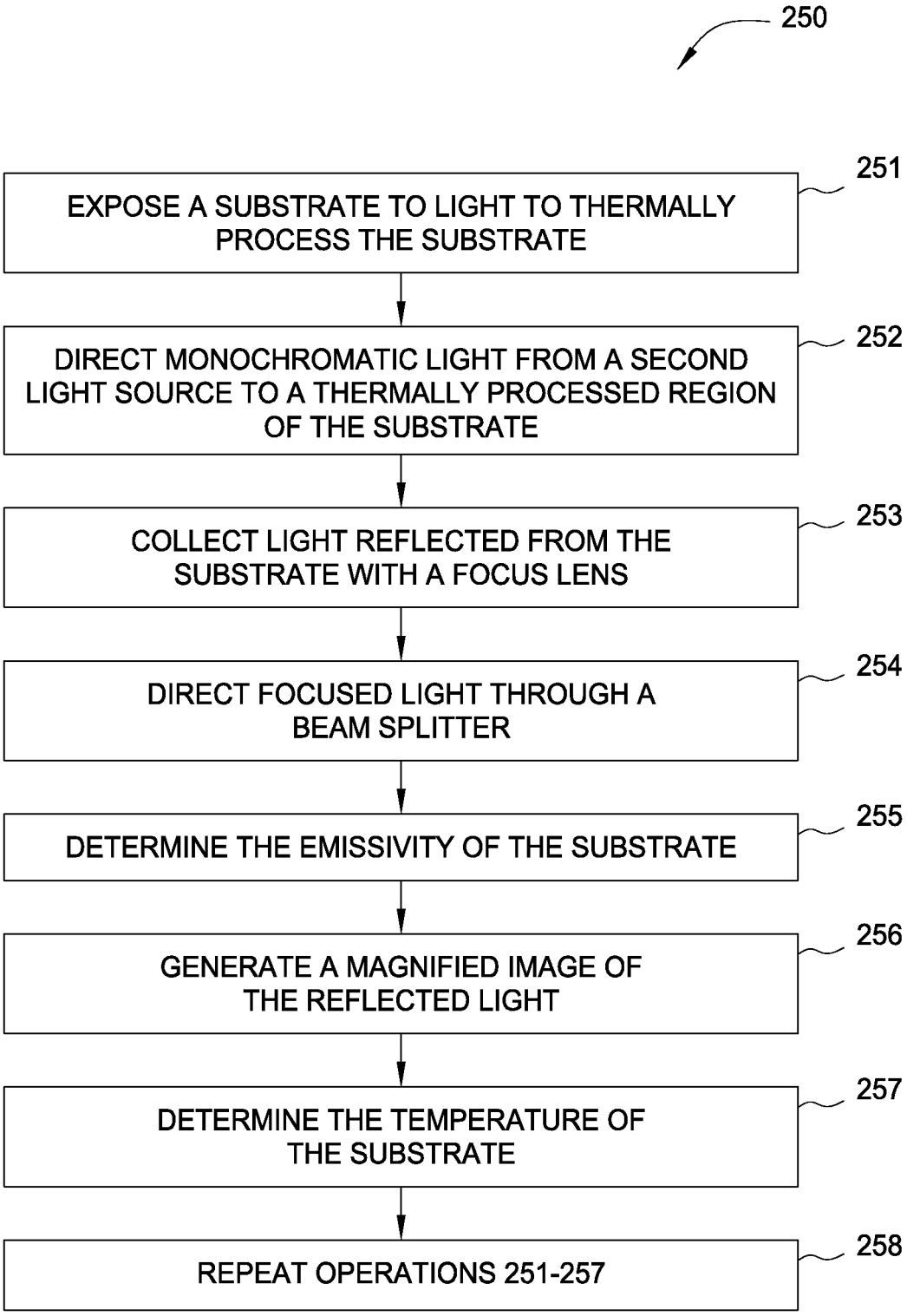

250
EXPOSE A SUBSTRATE TO LIGHT TO THERMALLY PROCESS THE SUBSTRATE
251
DIRECT MONOCHROMATIC LIGHT FROM A SECOND LIGHT SOURCE TO A THERMALLY PROCESSED REGION OF THE SUBSTRATE
252
COLLECT LIGHT REFLECTED FROM THE SUBSTRATE WITH A FOCUS LENS
253
DIRECT FOCUSED LIGHT THROUGH A BEAM SPLITTER
254
DETERMINE THE EMISSIVITY OF THE SUBSTRATE
255
GENERATE A MAGNIFIED IMAGE OF THE REFLECTED LIGHT
256
DETERMINE THE TEMPERATURE OF THE SUBSTRATE
257
REPEAT OPERATIONS 251-257
258

FIG. 2

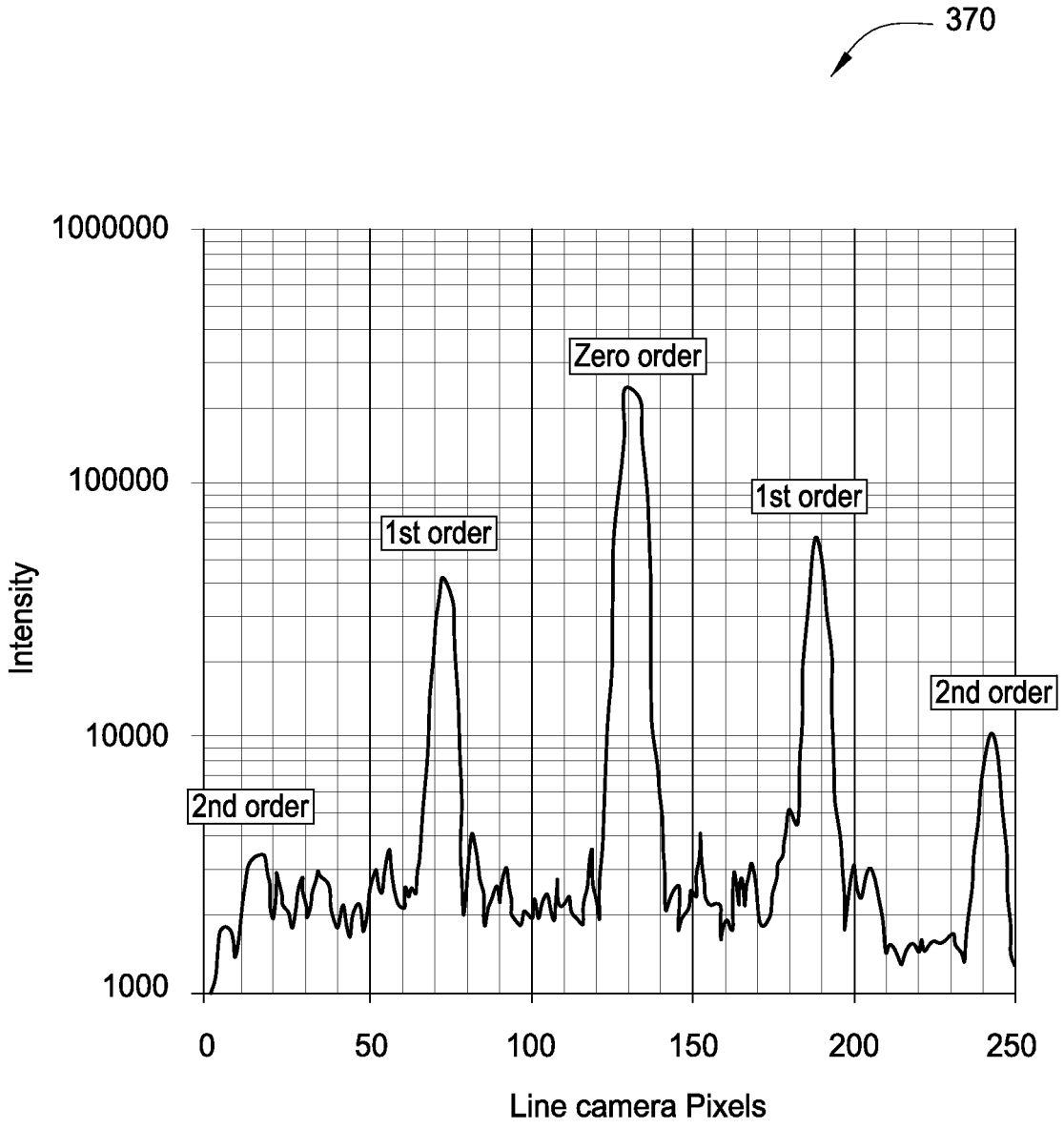

370
1000000
100000
10000
1000
Intensity
Zero order
1st order
1st order
2nd order
2nd order
0
50
100
150
200
250
Line camera Pixels

FIG. 3

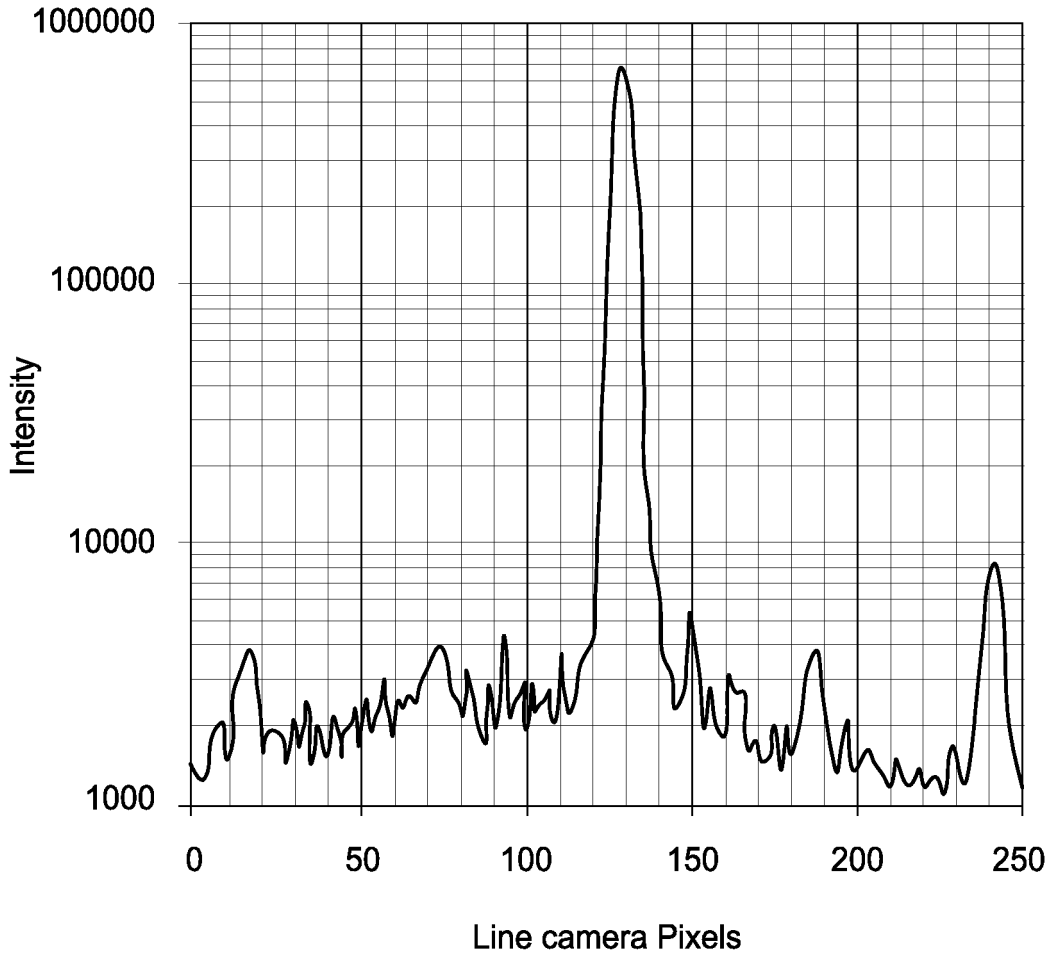

1000000
100000
10000
1000
Intensity
0
50
100
150
200
250
Line camera Pixels

FIG. 4A

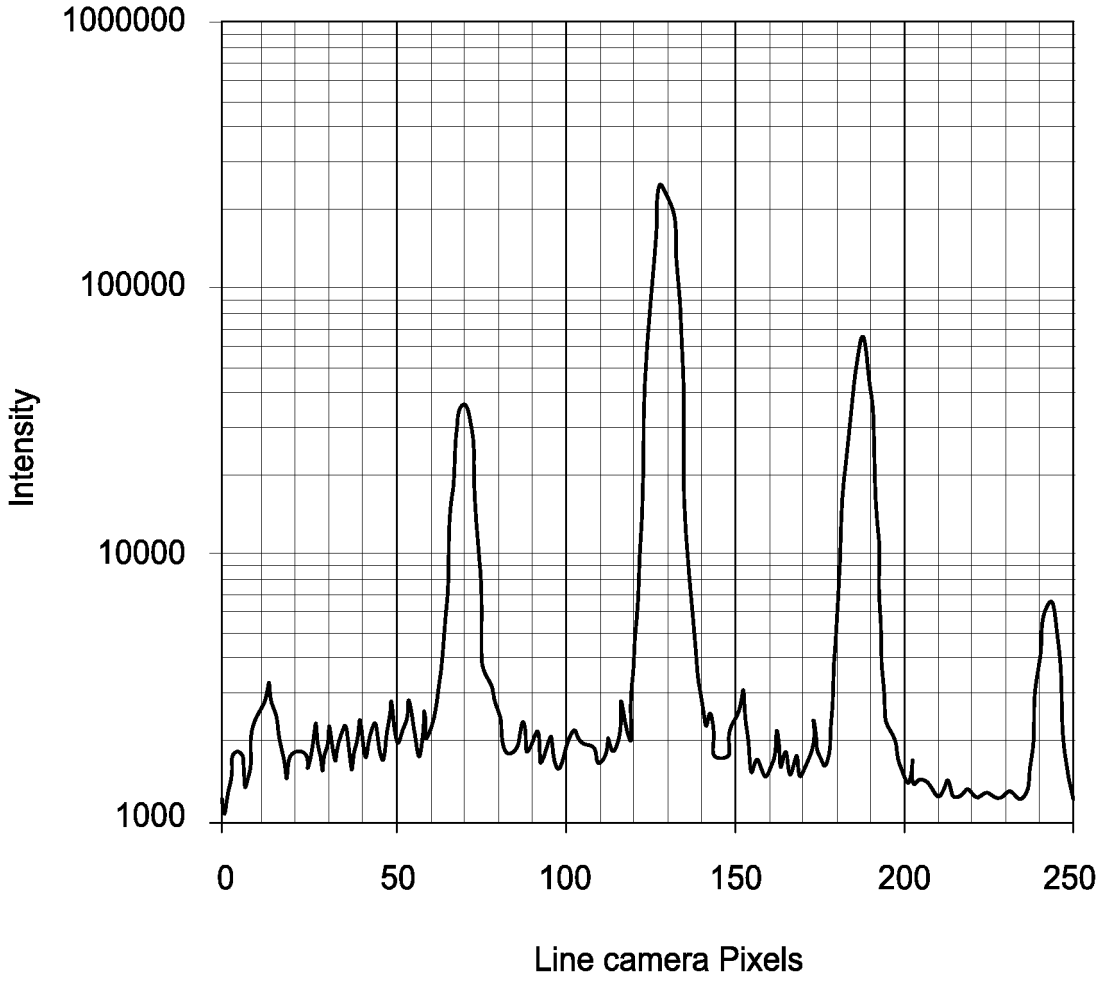

1000000
100000
10000
1000
Intensity
0
50
100
150
200
250
Line camera Pixels

FIG. 4B